

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Rosengaus et al.

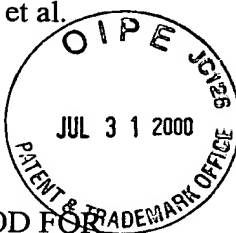
Attorney Docket No.: KLA1P001C1

Application No.: 09/474,941

Examiner: Rosenberger, R.

Filed: December 30, 1999

Group: 2877

Title: SYSTEM AND METHOD FOR
INSPECTING SEMICONDUCTOR
WAFERS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Assistant Commissioner for Patents, Washington, DC 20231 on July 25, 2000.

Signed: _____

Agnes F. Spence

Assistant Commissioner for Patents
Washington, DC 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE	LARGE ENTITY RATE FEE
TOTAL CLAIMS	20	22	0	X 9 = \$	OR X18 = \$0
INDEP CLAIMS	4	4	0	X39 = \$	OR X78 = \$0

[] Multiple Dependent Claim Present
and Fee Not Previously Paid

\$130=\$0

\$260= \$0

TOTAL

\$ _____

\$0

- ☐ Applicant(s) hereby petition for a _____(s) extension of time to respond to the aforementioned Office Action .
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0388.
- ☐ Enclosed is our Check No. _____ in the amount of \$ _____ to cover the additional claim fee and/or extension of time fees.
- ☒ Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 50-0388 (Order No.KLA1P001C1). A copy of this sheet is enclosed.

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP

Phillip P. Lee

Reg. No. P - 46,866

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Agnes F. Spence

AMENDMENT A

RECEIVED
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Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir or Madame:

In response to the Office Action dated April 25, 2000, a response to which is due July 25, 2000 please enter the following amendments and consider the following remarks:

IN THE CLAIMS:Please CANCEL claim 2 and 7 without prejudice or disclaimer.Please AMEND claims 1, 6 and 17 as follows:

1. (Twice Amended) An integrated circuit manufacturing system comprising:
- (a) a plurality of interrelated integrated circuit manufacturing tools capable of operating in parallel on a plurality of semiconductor wafers, wherein the plurality of interrelated integrated circuit manufacturing tools comprise a cluster tool;
 - (b) a modular optical inspection system including
 - a plurality of modular inspection subsystems each configured to detect defects on a portion of a semiconductor wafer,